

Form PTO 1449
(Modified)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.
292627US2X PCTSERIAL NO.
10/583,718

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT
Julien CHARTON, et al.FILING DATE
June 20, 2006

GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
/K.T./	AA	2002 0171327	11-21-02	MILLER, Samuel Lee et al.			
	AB						
	AC						
	AD						
	AE						
	AF						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
/K.T./	AG	92 22763	12-23-92	WO		NO
	AH					
	AI					
	AJ					
	AK					
	AL					
	AM					

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

/K.T./	AN	AKSYUK, V. A. et al., "Optically-Powered Optical Power Limiter for Use in Lightwave Networks", Bell Laboratories, Lucent Technologies, pgs. 344-348, 1999. no month provided
/K.T./	AO	BIFANO, Thomas G. et al., "Continuous-Membrane Surface-Micromachined Silicon Deformable Mirror", Optical Engineering, Vol. 36, No. 5, pgs. 1354-1359, 1997. may, 1997
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/K.T./	AQ	VAN DER WIJNGAART, Wouter et al., "A High-Stroke, High-Pressure Electrostatic Actuator for Valve Applications", Sensors and Actuators, Vol. 100, No. 2-3, pgs. 264-271, 2002. no month provided
/K.T./	AR	ZHOU, T. et al., "MEMS-Based 14GHz Resolution Dynamic Optical Filter", Electronics Letters, Vol. 39, No. 24, pgs. 1-2, 2003. november, 2003
/K.T./	AS	BRANEBJERG, Jens et al., "A New Electrostatic Actuator Providing Improved Stroke Length and Force", Micro Electro Mechanical Systems, pgs. 6-12, 1992. february 1992
/K.T./	AT	GILBERT, J.R. et al., "Two-Phase Actuators: Stable Zipping Devices Without Fabrication of Curved Structures", Solid-State and Actuator Workshop, pgs. 98-100, 1996. no month provided
/K.T./	AU	DIVOUX, C. et al., "A Novel Electrostatic Actuator for Micro Deformable Mirrors: Fabrication and Test", TRANSDUCERS, Solid-State Sensors, Actuators and Microsystems, Vol. 1, pgs. 488-491, 2003. no month provided
	AV	
	AW	
	AX	
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	AZ	

☐ Additional References sheet(s) attached

Examiner /Karl Tamai/

Date Considered 03/25/2009

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

	Docket No.: 292627US2X PCT	Serial No.: 10/583,718
LIST OF RELATED CASES CITED BY APPLICANT UNDER 37 CFR 1.56	Inventor: Julien CHARTON, et al.	
	Filing Date: June 20, 2006	Group:

LIST OF RELATED CASES

<u>Examiner Initial</u>	<u>Docket No.</u>	<u>Serial or Patent Number</u>	<u>Filing or Issue Date</u>	<u>Patent App. Publication No.</u>	<u>Inventor or Applicant</u>
/K.T./	292627US2XPCT*	10/583,718	06/20/06	<u>20070103843</u>	CHARTON et al.
/K.T./	292748US2PCT	10/584,202	06/23/06	<u>20070120438</u>	DIVOUX
/K.T./	292628US0 PCT	10/583,719	06/20/06	<u>20070137989</u>	DIVOUX et al.
/K.T./	292962US2	11/472,377	06/22/06	<u>20060291129</u>	CHAPPAZ et al.

Examiner /Karl Tamai/

Date Considered 03/25/2009

*Present Application; listed for information

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